

Performance Analysis of CMOS Circuits using Shielded Channel Dual Gate Stack Silicon on Nothing Junctionless Transistor



S.C. Wagaj, S.C. Patil

Abstract: In this paper it has been demonstrated that a shielded channel made by varying the side gate length in silicon-on-nothing junctionless transistor not only improves the short channel effect but also improve the performance of CMOS circuits of this device. The proposed device shielded channel dual gate stack silicon on nothing junctionless transistor (SCDGSSONJLT) drain induced barrier lowering (DIBL), cut-off frequency and subthreshold slope are improved by 20%, 39% and 20% respectively over the single material gate silicon on insulator junctionless transistor (SMG SOI JLT). The proposed device CMOS inverter fall time T_f (pS) and noise margin improves by 50% and 10% compare to shielded channel silicon on insulator junctionless transistor (SCSOIJLT). It has been observed that circuit simulation of CMOS inverter, NAND and NOR of proposed device. The static power dissipation in the case of proposed SCDGSSONJLT device are reduced by 45%, 81% and 83% respectively over the SMGSOIJLT. Thus, significant improvement in DIBL, cut-off frequency, propagation delay and static power dissipation at low power supply voltage shows that the proposed device is more suitable for low power CMOS circuits.

Keywords: Shielded channel, junctionless transistor, dual gate stack, silicon on nothing, NAND gate, NOR gate.

It has been observed that bulk planner junctionless transistor [6] and junctionless double gate transistor are having low leakage current due to high channel doping. Moreover, due to high channel doping the mobility reduces due to ionization scattering and subsequently results in lower transconductance [6] [7]. To overcome these challenges, many authors have introducing solutions such as junctionless nanowire transistor with a dual material gate [8], dual material gate junctionless transistor with high-k spacer [9], dual material gate silicon on nothing junctionless transistor [10], dual material double gate junctionless transistor considering fringing field [11], charge plasma based transistor with induced graded channel [12], gate-all-around junctionless transistor [13], non-uniformly doped symmetric double gate junctionless transistor [14], have been proposed. Among these junctionless transistor and architecture, dual material double gate junctionless transistor is best candidate for CMOS logic circuits [15]. However, it has been observed that

I INTRODUCTION

This International technological road map for semiconductor nanoscale with junction transistor's shallow junction formation is very challenging in fabrication. Author colinge et.al have introduced junctionless transistor with uniform doping of source, channel and drain region [1]. The electric field perpendicular to the channel is significantly very low in junctionless transistor means mobility degradation is very less [2] [3]. However, in junctionless transistor improving the current driving capability and gate control on channel potential are the challenges in this device. To overcome the short channel effect problem related with nanoscale junctionless transistor, double gate junctionless transistor can be considered [4] [5].

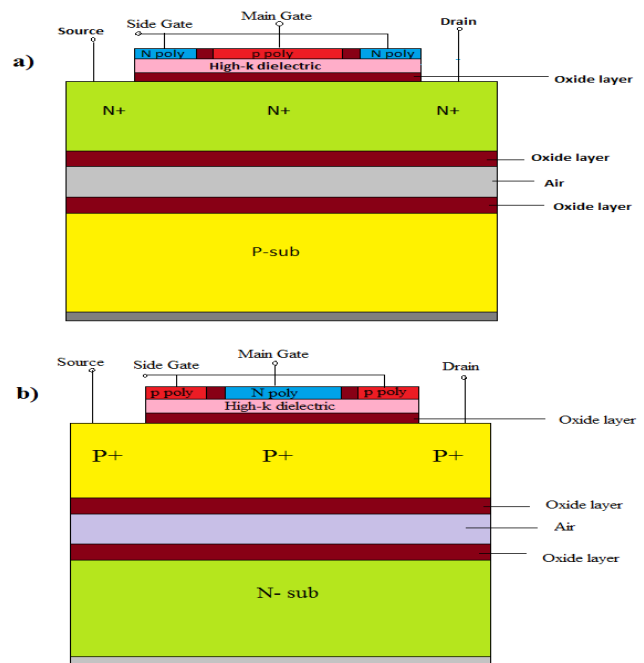


Figure 1. a) Proposed n-channel b) proposed p-channel SCDGSSONJLT structures used in COGENDA TCAD simulations

Manuscript received on May 02, 2021.

Revised Manuscript received on July 13, 2021.

Manuscript published on August 30, 2021.

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dual material double gate with high-k spacer leads to an increase in gate capacitance and decrease in cut-off frequency [9]. Along with increases in device parameter fluctuations limits the scalability of junctionless transistor is the short channel effect. DIBL effect problem and excess parasitic capacitance arrive in SOI MOSFET due to charge accumulated in the thick buried layer. Air is insulating layer dielectric constant is unity. Buried oxide layer is removed by air and a structure is proposed as silicon-on-nothing MOSFET. Parasitic capacitance values between source/drain and substrate are induced in the silicon on nothing (SON) structure, and therefore a higher circuit speed can be expected with SON device [16]. Due to double layer gate stack design the output characteristics are improved. The drain bias variations and enhanced and the gate control on the channel charge is increased. The channel length of the proposed work 20nm [17], to reduce device gate leakage current and low off state current requirements the high-k dielectric is considered as an alternative to SiO₂. The concept of double layer gate stack and silicon on nothing has been studied on various device architecture such as dual material double layer gate stack SON MOSFET[18], dual material double gate SON MOSFET[19], High-k gate stack properties in SON MOSFET, dual material double layer gate stack junctionless transistor[20]. Amin s and Sarin R.K. et.al demonstrate doping less dual material and gate stack architecture of junctionless transistor with high-k spacer and misaligned double gate JLT [21][22]. Although the concept of double layer gate stack SON has been widely studied on various device architectures, the effect of two layer gate stack and SON junctionless transistor for CMOS circuit has not been reported in earlier literature to the best of my knowledge. In our earlier work shielded channel junctionless transistor was proposed by reducing the short channel effects. Here the reduced DIBL effect was observed by varying side gate length and increased ON current due to workfunction difference of side gate [15].

In this paper, we demonstrate the CMOS circuit implementation using N and P channel SCDGSSONJLT. A comparison of SCDGSSONJLT with SMG SOI JLT and SCSOIJLT is performed. Performance parameters such as static power dissipation, propagation delay, noise margin, rise and fall time of CMOS inverter, NAND and NOR are thoroughly investigated. For the simulation COGENDA TCAD tool is used.

This paper is arranged as follows. Section II consist device structure and their dimensions used for simulation are presented. The methodology is also highlighted. The result and discussion are given in section III. Conclusion is presented in section IV.

II. DEVICE STRUCTURE AND SIMULATION

Six different types of MOSFETs are used to implement CMOS circuits in this paper: namely, p- and n-channel SCDGSSONJLT and p- and n-channel SMGSOIJLT and p- and n- channel SCSOIJLT. The schematic device structure of the SCDGSSONJLT is shown in Figure 1. Performance analysis for CMOS inverters is done for three different channel length 20nm, 30nm and 40nm as per the international technology roadmap for semiconductors (ITRS) [18]. The

parameters considered for the simulation are main gate 4.77eV, side gate 4.5eV, channel donor doping $N_D=0.4 \times 10^{18} \text{ cm}^{-3}$, channel thickness $t_{si}=10\text{nm}$, gate oxide thickness 3nm (1nm SiO₂ and 2nm HfO₂), substrate doping $N_A=1 \times 10^{16} \text{ cm}^{-3}$ respectively. A buried oxide thickness (t_{box}) is of 10nm (two oxide layer 2nm each and air thickness 6nm). Table 1 Device parameters used in simulation summarizes device parameters use in this simulation.

Table1: Device parameters used in simulation

Sr. No.	Parameters	Smgsoijlt	Scsoijlt	Scdgssoijlt
1	Main Channel length (nm)	20	20	20
2	Side gate channel length (nm)	-	10	10
3	Work function of main gate (eV)	4.9	4.9	4.9
4	Work function of Side gate (eV)	-	4.17	4.17
5	Channel thickness (nm)	10	10	10
6	Channel doping density N_D (cm^{-3})	0.4×10^{18}	0.4×10^{18}	0.4×10^{18}
7	Buried oxide (nm)	10	10	SiO ₂ -2 Air-6 SiO ₂ -2
8	P-sub (nm)	20	20	20
9	Gate oxide (nm)	3	3	HfO ₂ -2 SiO ₂ -1
10	Equivalent gate oxide thickness (nm)	3	3	1.312

Genius uses the Kane's model [23] to calculate the carrier generation by band-band tunnelling G^{BB} . The expression for the generation rate of for electrons and holes is as shown in equation 1

$$G^{BB} = A.BTBT \cdot \frac{E^2}{\sqrt{E_g}} \cdot \exp(-B.BTBT \cdot \frac{E_g^{3/2}}{E}) \quad (1)$$

Where- E is the magnitude of electrical field; E_g is the band-gap of the material, A.BTBT and B.BTBT are empirical fitting parameters.

The default values for silicon are:

$$\begin{aligned} A_BTBT &= 3.500000E+21 \\ B_BTBT &= 2.250000E+07 \end{aligned}$$

Lombardi Surface Mobility Model

The Lombardi mobility model [24] is an empirical mobility model shown in equation 2. The mobility model consist three different components as like surface roughness, phonon scattering and doping dependent mobility model. Bulk mobility model in Lombardi mobility model is similar to masetti's model.



$$\mu_b = \mu_0 \exp\left(-\frac{P_c}{N_{tot}}\right) + \frac{\mu_{max} - \mu_0}{1 + \left(\frac{N_{tot}}{C_r}\right)^\alpha} - \frac{\mu_1}{1 + \left(\frac{C_s}{N_{tot}}\right)^\beta} \quad (2)$$

$$\mu_{max} = \mu_2 \left(\frac{T}{300}\right)^\xi$$

$$\alpha = 0.680, \beta = 2.0, \xi = 2.5, \mu_0 = 52.2 \text{ cm}^2 / \text{v.s},$$

$$\mu_2 = 1417 \text{ cm}^2 / \text{v.s}, C_s = 3.43 \times 10^{20} \text{ cm}^{-3}, C_r = 9.68 \times 10^{16} \text{ cm}^{-3}$$

Carrier recombination, generation model, Fermi Dirac statics and impact ionization models and Lombardi mobility model in COGENDA TCAD. The quantum confinement model also have been incorporated in the simulation.

III. MODEL CALIBRATION

To ensure the validity of results, initially calibration of simulation models is done with reference to simulation result of MOSFET characteristics presented in [9] and n-channel JLT [5]. Thus the model characteristic is shown in Figure 2. and Figure 3. There is good agreement of COGENDA TCAD simulated and simulated result of different researchers is evident in these figures.

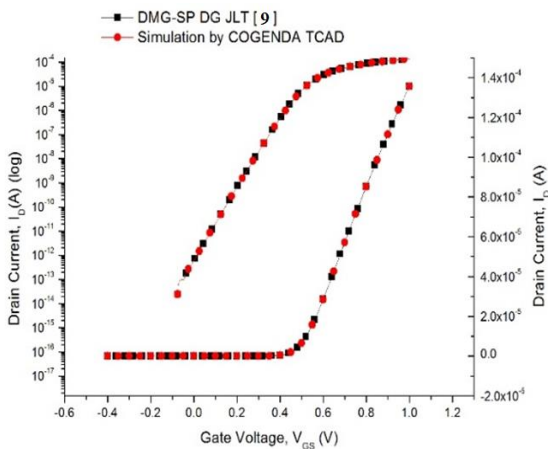


Figure 2. Drain current of DMG-SP DGJLT with gate voltage at $V_{DS}=50\text{mv}$, $L=40\text{nm}$, $T_{si}=10\text{nm}$, $T_{ox}=1\text{nm}$, both linear and log scale compare with COGENDA TCAD

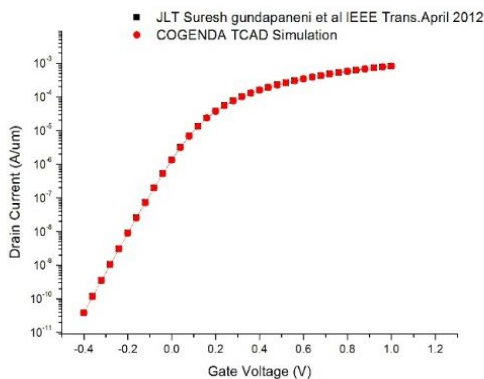


Figure 3. $I_D - V_G$ plot for a JLT. $L_G=20\text{nm}$, $T_{si}=6\text{nm}$, $N_D=10^{19}$, $\Phi_m=5.1\text{ev}$, $T_{ox}=1\text{nm}$, $V_D=1\text{V}$.

IV. RESULTS AND DISCUSSIONS

1.1 Performance comparison of SCDGSSONJLT and SCISOJLT

SCDGSSONJLT's subthreshold slope, drain induced barrier lowering (DIBL) and cut-off frequency are improved by 20%, 20% and 39% respectively over the single material gate silicon on insulator junctionless transistor (SMG SOI JLT). The $I_D - V_{DS}$ characteristics are shown in Figure 4. Figure 4 compares the transfer characteristics of n channel and p channel SCDGSSONJLT with SCISOJLT. The main reason for this improvement is, reduction of the effective gate oxide of thickness of n type SCDGSSONJLT due to dual gate stack design (1.312nm). Output characteristics of n and p channel SCDGSSONJLT enhanced compare to SCISOJLT at a fixed $V_{GS}=1.5\text{V}$, work function main gate=4.9eV, side gate=4.17eV, $N_D=0.4 \times 10^{18} \text{ cm}^{-3}$.

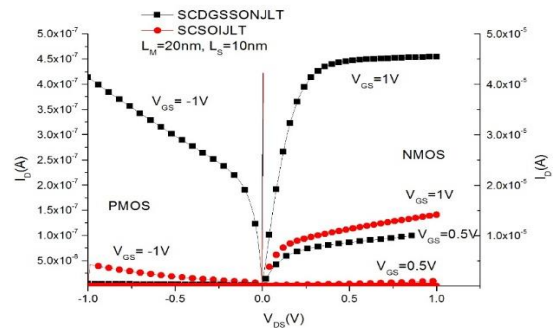
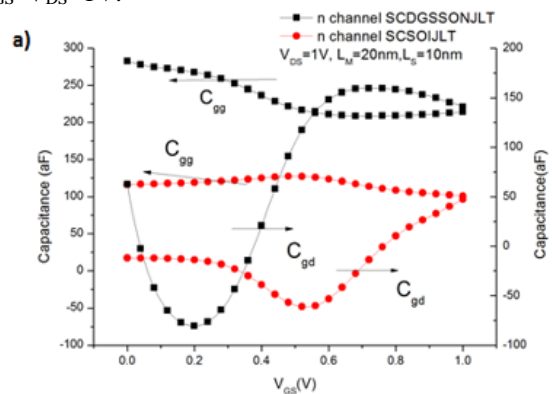


Figure 4. I_D vs V_{DS} characteristics of shielded channel JLT and proposed n-channel and p-channel SCDGSSONJLT at different V_{GS} values

The electric field in the channel increase due to side gate biasing. Due to high electric field in the channel velocity of electron increases. The ON state current of SCISOJLT is lower due to high doping density. In presence of the effect of using high-k/ SiO_2 gate-stack architecture on the transfer characteristics of SCDGSSONJLT and SCISOJLT. The advantage of gate stack in terms of increased I_{ON} . ON current of SCDGSSONJLT is $45.4\mu\text{A}$ and for SCISOJLT is $14.1\mu\text{A}$ at $V_{GS}=V_{DS}=1\text{V}$.



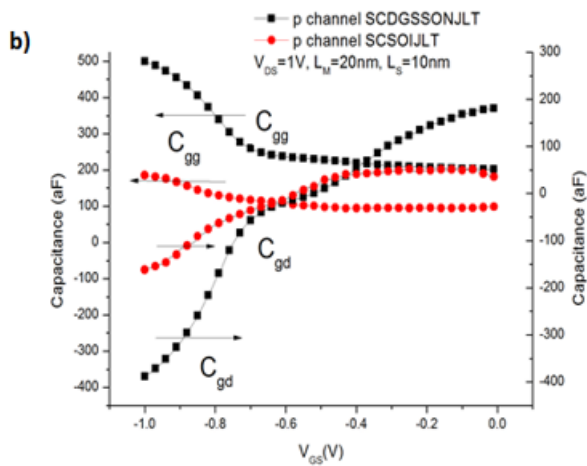


Figure 5. Comparison of gate capacitance and gate-to-drain capacitances between SCDGSSONJLT and SCSOIJLT 20nm channel length a) n-channel device and b) p-channel device.

Figure 5 shows that comparison of gate to drain capacitance C_{gd} and gate capacitance C_{gg} for n & p channel as a function of the gate-to-source voltage V_{GS} between SCDGSSONJLT and SCSOIJLT. The gate capacitance C_{gg} consist of the series combination of gate to channel capacitance and gate oxide capacitance.

Capacitance components C_{gg} , C_{gs} and C_{gd} have the relationship $C_{gg}=C_{gs}+C_{gd}$ (3)

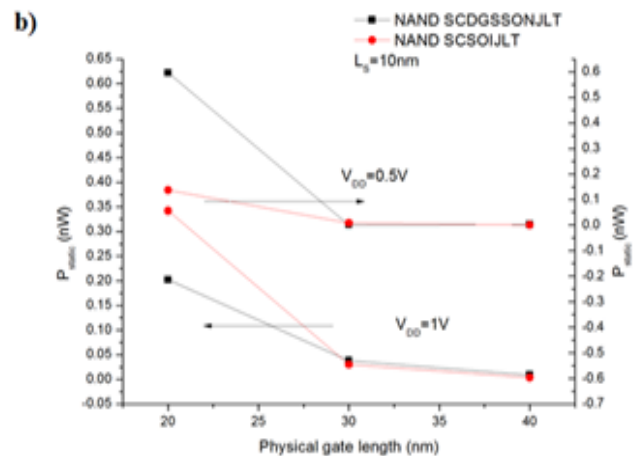
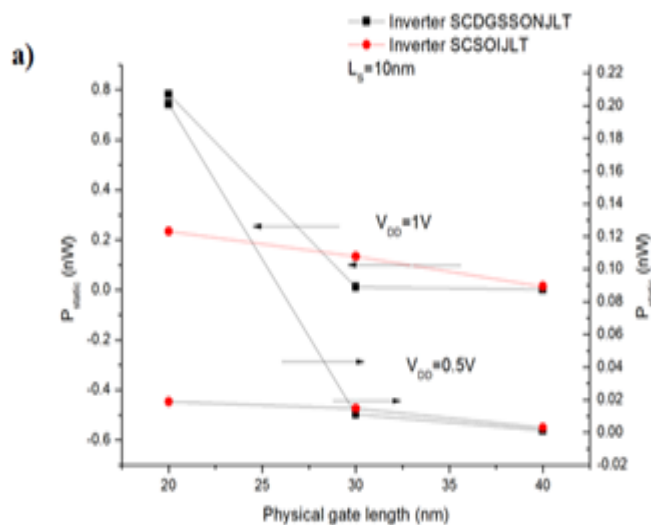
Gate oxide capacitance C_{ox} can be evaluate as [25]

$$C_{ox} = \frac{2\pi\epsilon_s L_g}{\ln\left(1 + \frac{t_{ox}}{R}\right)} \quad (4)$$

Table 2: Delay and static power dissipation of inverters

L_G In nm	Inverter SCDGSSONJLT				Inverter SCSOIJLT			
	$V_{DS}=1V$		$V_{DS}=0.5v$		$V_{DS}=1v$		$V_{DS}=0.5v$	
	P_{static} (W)	τ_p (pS)	P_{static} (W)	τ_p (pS)	P_{static} (W)	τ_p (pS)	P_{static} (W)	τ_p (pS)
20	7.82×10^{-10}	10	2.01×10^{-10}	50	2.34×10^{-10}	10	1.89×10^{-11}	70
30	3.37×10^{-11}	19	1.10×10^{-11}	20	1.34×10^{-10}	20	1.47×10^{-11}	70
40	3.21×10^{-12}	24	1.26×10^{-12}	20	1.43×10^{-11}	30	2.78×10^{-12}	110

In transient response gate capacitance role is very important. It is observed that C_{gd} for the SCDGSSONJLT are lower than that for SCSOIJLT. In linear region 0.275fF capacitance at $V_{GS}=0.08V$ and $V_{DS}=1V$ for SCDGSSONJLT and 0.117fF capacitance at $V_{GS}=0.08V$ and $V_{DS}=1V$ for SCSOIJLT and in saturation region 0.2fF capacitance at $V_{GS}=V_{DS}=1V$ of SCDGSSONJLT and 0.1fF capacitance at $V_{GS}=V_{DS}=1V$ of SCSOIJLT.



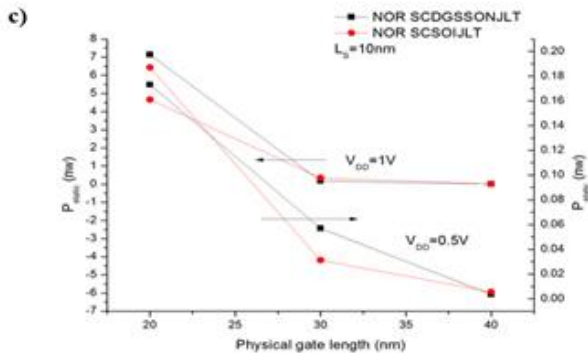


Figure 6. Comparison of static power dissipation of a) CMOS inverter, b) NAND gate and c) NOR gate circuit based on SCSOIJLT and proposed SCDGSSON junctionless transistor at various channel lengths.

All the capacitances are simulated as simulation mode AC sweep at a frequency of 1MHz. The SCDGSSONJLT has highest C_{gg} compared with SCSOIJLT. This is attributed to high-k gate stack.

Figure 6 shows the plot between static power dissipation v/s physical gate length for $V_{DS}=1V$ (LHS) and $V_{DS}=0.5V$ (RHS) for inverter, NOR and NAND gate. The channel length consider for this simulation are 20nm, 30nm and 40nm and side gate length is 10nm which is constant for SCDGSSONJLT and SCSOIJLT. It has been observed that OFF current of MOSFET as well as static power dissipation decreases due to high-k gate stack.

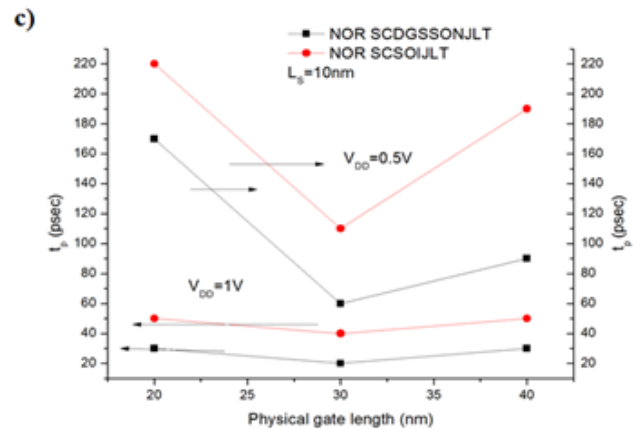
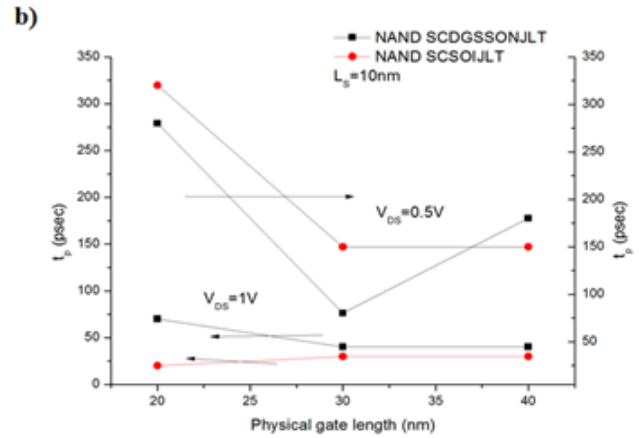
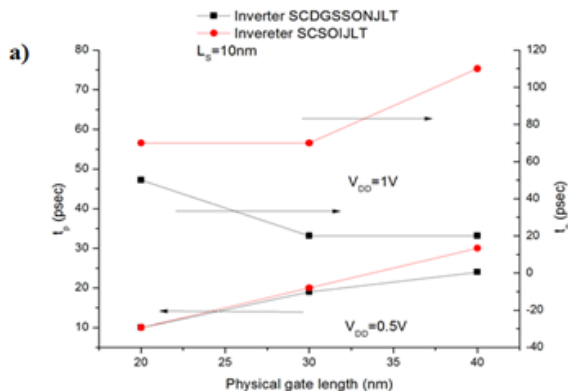


Figure 7. Comparison of propagation delay of a) CMOS inverter, b) NAND gate and c) NOR gate circuit based on SCSOIJLT and proposed SCDGSSON junctionless transistor at various channel length.

Table 2 summarize CMOS inverter P_{static} and τ_p values for $V_{DS}=0.5V$ and $1V$. At $V_{DD}=0.5V$ and channel length 30nm, 40nm of SCDGSSONJLT inverter static power dissipations are 11pW,

Table-3 Circuit performance parameters for different L_s .

Side gate length (nm)	Transient Response of Inverters					
	Rise Time, T_r (pS)			Fall time T_f (pS)		
	Inverter-1 SCDGSSONJLT	Inverter-2 SCSOIJLT	Improvement	Inverter-1 SCDGSSONJLT	Inverter-2 SCSOIJLT	Improvement
10	105	150	30%	95	180	47%
20	105	130	19%	130	110	NIL
30	140	119	NIL	100	118	15%
40	140	140	NIL	190	130	NIL

1.26pW respectively, and SCSOIJLT inverter static power is 14.7pW. The static power dissipation of SCDGSSONJLT NOR gate is 3.55pW at $V_{DD}=0.5V$ and channel length of 40nm. The static power dissipation is 5.55pW for SCSOIJLT NOR gate. Static power dissipation of SCDGSSONJLT is minimum due to high phonon scattering below threshold voltage. Figure 7 shows the graph between propagation delay v/s physical channel length of SCDGSSONJLT and SCSOIJLT inverter, NAND and NOR gate. Propagation delay of SCDGSSONJLT is minimum as compared to SCSOIJLT. The delay time τ_d is defined as $\tau_d = (\tau_r + \tau_f)/2$, where the rise time τ_r and the fall time τ_f are extracted at $V_{out} = V_{dd}/2$. Device aspect ratio of SCDGSSONJLT device is 50 because channel length is 20nm and width is 1 μ m. When Channel length increases then propagation delay of inverter SCDGSSONJLT decreases and propagation delay of SCDGSSONJLT reduces by 20% as compared to SCSOIJLT. Propagation delay of SCSOIJLT is 110ps and proposed SCDGSSONJLT is 20ps at $V_{DS}=0.5V$ at channel length 40nm. SCDGSSONJLT NOR gate propagation delay is improved by 22%, 45% and 52% over the SCSOIJLT at channel length 20, 30 and 40nm respectively at $V_{DS}=0.5V$. Proposed SCDGSSONJLT is best candidate for low power CMOS circuit.

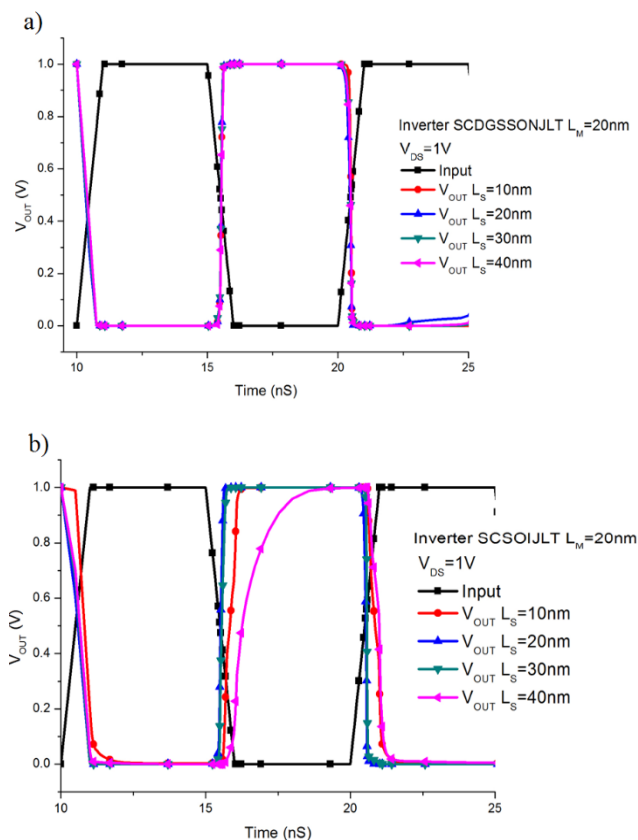


Figure 8. Transient response of CMOS inverter a) proposed SCDGSSONJLT b) SCSOIJLT at different side gate length.

Figure 8 a and b shows that the transient response of CMOS inverter SCDGSSONJLT and SCSOIJLT, it is useful for different side gate length calculation of propagation delay (τ_p). Propagation delay indicates that time require by CMOS inverter to switch from OFF state to ON state. When

propagation delay increases then lower will be the speed of device. It has been observed that SCDGSSONJLT exhibits smallest propagation delay of 20ps and SCSOIJLT has larger propagation delay that is 30ps. Voltage overshoot and undershoot effect leads in the transient response due to C_{gd} . In SCSOIJLT the undershoot peak arises due to the larger C_{gd} . Table 3 summarizes transient response inverters for different side gate lengths at $V_{DS}=1V$. SCDGSSONJLT and SCSOIJLT inverters rise time (τ_r) and fall time (τ_f) are calculated from transient characteristics at a different side gate channel length as shown in table 3.

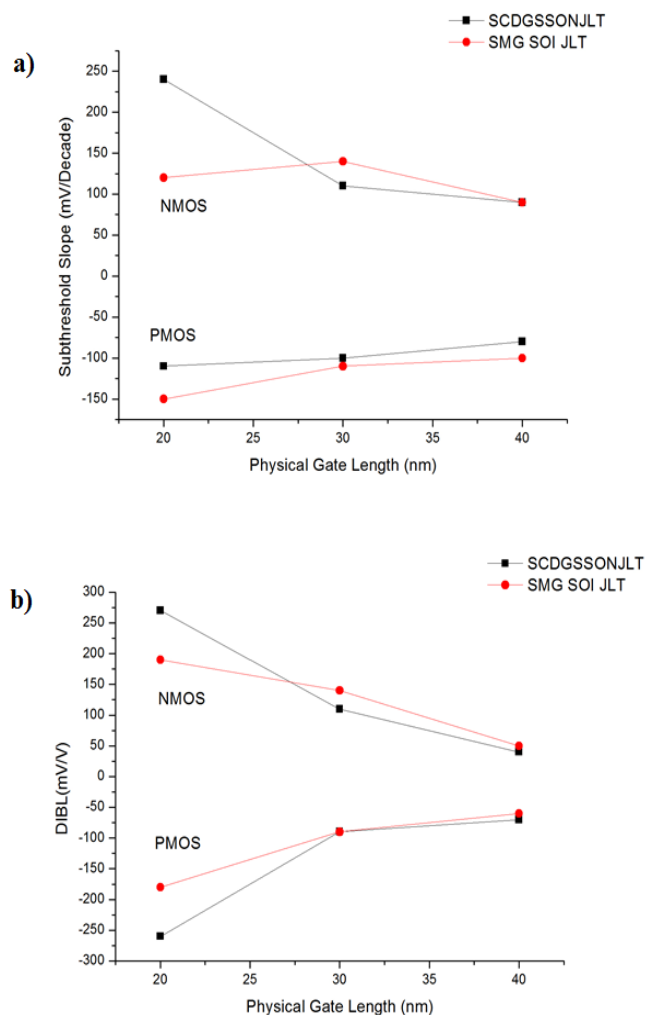


Figure 9. Comparison of a) Subthreshold swing, b) drain induced barrier lowering with physical channel length of SCDGSSON and SMGSOI n-channel and p-channel junctionless transistor at $V_{SGS}=1.5V$.

If SCDGSSONJLT side gate length increases from 10nm to 20nm then current is remains constant, hence rise time also remains constant. The side gate length increases from 20nm to 30nm then

Table-4 Device parameters for different channel length

Values used for simulation		Simulated values							
Channel length(nm)	V _{DS} (V)	SCDGSSONJLT n-type		SCDGSSONJLT p-type		SMGSOIJLT n-type		SMGSOIJLT p-type	
		I _{ON} (μA)	V _T (mV)	I _{ON} (μA)	V _T (mV)	I _{ON} (μA)	V _T (mV)	I _{ON} (μA)	V _T (mV)
20	1	45.4	410	-	-	83.7	190	59.2	850
20	0.05	11.7	680	-	-	51.3	380	23	1030
30	1	78.4	430	17.1	1150	71.9	430	59.2	950
30	0.05	36.6	550	4.8	1500	20.3	570	17.7	1040
40	1	74.3	510	17	1140	79.4	350	54.7	980
40	0.05	34.6	780	4.7	1210	31.9	400	12.9	1040

Channel potential shift away from main channel length. The current driving capability decreases then rise time increases from 10ps to 20ps and side gate length increases from 30nm to 40nm then drain current is remains constant means rise time remains constant. It is observe in τ_r for SCDGSSONJLT is lower than that of SCSOIJLT at side gate length of 20, 30 and 40nm. It has been observed that rise time of both inverter remains constant. Figure 10 shows that voltage transfer curve (VTC) of CMOS inverter with SCDGSSONJLT is approximately similar to CMOS inverter with SCSOIJLT having the same effective channel length i.e. L=20nm. Figure 10 shows that noise margin is calculated from butterfly graph of voltage transfer characteristics. The noise margin defined as maximum acceptable noise voltage in input that will not change the output voltage. It has been observed that the higher noise margin is in SCDGSSONJLT inverter as compared to SCSOIJLT inverter at same effective channel length. Thus, SCDGSSONJLT CMOS circuit is more suitable for digital application such as memory design which is affect on read and write margin as compared with SCSOIJLT CMOS circuit. Noise Margin at low state (NM_L) of SCDGSSONJLT is 0.39V and SCSOIJLT is 0.34V. Noise Margin at high state (NM_H) of SCDGSSONJLT is 0.32V and SCSOIJLT is 0.39V where NM_H and NM_L are calculated using following equation. Noise margin at channel length 30nm is 0.36V in high state and 0.37V in low state.

$$NM_H = V_{OHmin} - V_{IHmin}$$

$$NM_L = V_{OLmax} - V_{ILmax}$$

1.2 Comparison of SCDGSSONJLT and SMGSOIJLT

Multi material gate junctionless transistor improves the performance as compared to single material gate junctionless transistor. The different researchers demonstrates that multi material gate junctionless transistor is best candidate for CMOS design compare to single material gate junctionless transistor [9] [16]. In this section multi material gate SCDGSSONJLT's CMOS circuits logical performance compared with single material gate junctionless transistor. Figure 9 a shows a graph between subthreshold slope (SS) and physical gate length and Figure 9b shows the graph between DIBL and physical gate length for PMOS and NMOS. The DIBL is calculated from equation 5,

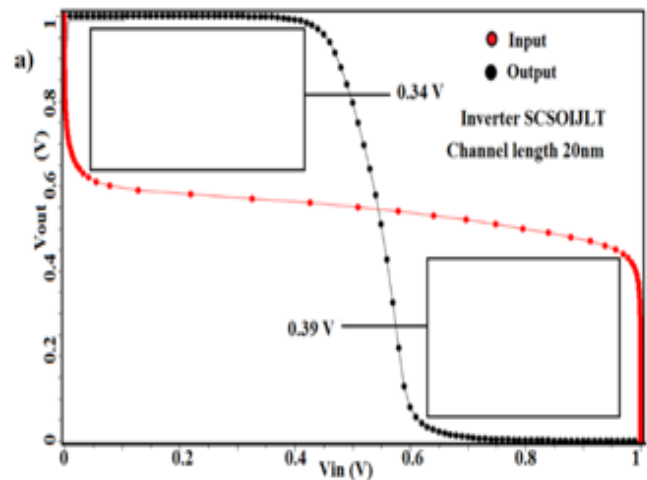
$$DIBL = \frac{V_{TLIN} - V_{TSAT}}{0.95} \tag{5}$$

Where V_{TLIN} is threshold voltage at V_{DS}=0.05V and V_{TSAT} as a threshold voltage at V_{DS}=1V and the poly gate work function is 4.77eV and n poly gate is 4.1eV. It can be seen that due to side gate biasing, the DIBL and SS are reduced for SCDGSSONJLT

as compared to SMG SOI JLT NMOS and PMOS devices. It has been observed that n-channel SCDGSSONJLT, the DIBL and SS are 40mV/V and 90 mV/decade and for SMGSOIJLT DIBL and SS are 50mV/V and 90mV/decade. The P-channel SCDGSSONJLT DIBL is -70mV/V and for SMGSOIJLT is -60mV/V at channel length 40nm. The sub-threshold current, I_{sub} can be expressed in terms of V_{TSAT} and SS as shown in equation 6 [26].

$$I_{sub} = I_0 \times 10^{-(V_{TSAT}/SS)} \tag{6}$$

I₀ is the drain current at V_{GS}=V_{TLIN} and SS can be expressed as



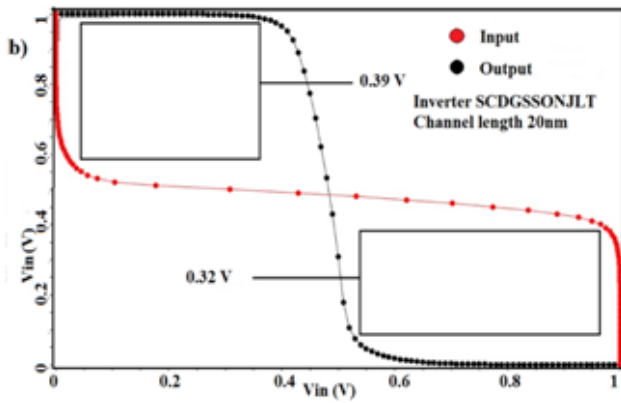


Figure 10. VTCs of CMOS inverter a) SC SOI b) proposed SCDGSSON junctionless transistor

$$SS = \frac{KT}{q} \ln(10) \left[1 + \frac{1}{C_{ox1}} \left(\frac{C_{si} \times C_{ox2}}{C_{si} + C_{ox2}} \right) \right] \quad (7)$$

C_{ox1} is gate capacitance and C_{ox2} is buried oxide capacitance and C_{si} is body channel capacitance $C_{si} = \epsilon_{si}/t_{si}$.

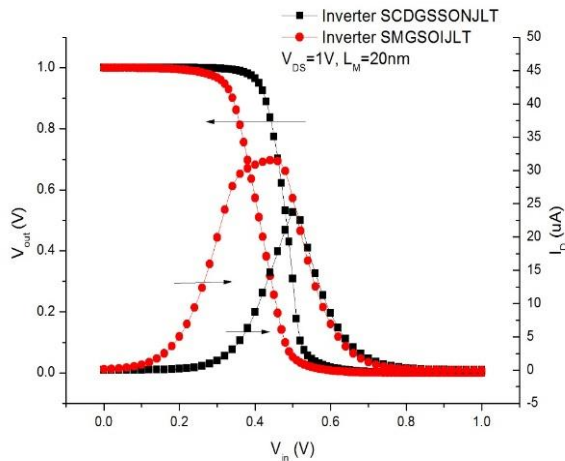


Figure 11. VTC for SCDGSSONJLT and SC SOIJLT for channel length 20nm

Figure 11 shows the voltage transfer characteristics and short circuit current (I_{SC}) of Inverter with SCDGSSONJLT and SMGSOIJLT inverter for supply voltage of $V_{dd}=1V$. The SMG SOI JLT inverter shows lower noise margin and higher short circuit current as compare to SCDGSSONJLT, which is related to the ON current properties of these devices. Short circuit current of SMGSOIJLT is maximum compared to SCDGSSONJLT. $23.7\mu A$ short circuit current of SCDGSSONJLT and $25.8\mu A$ of SMGSOIJLT and hence short circuit power dissipation of SMGSOIJLT is maximum compared to SCDGSSONJLT.

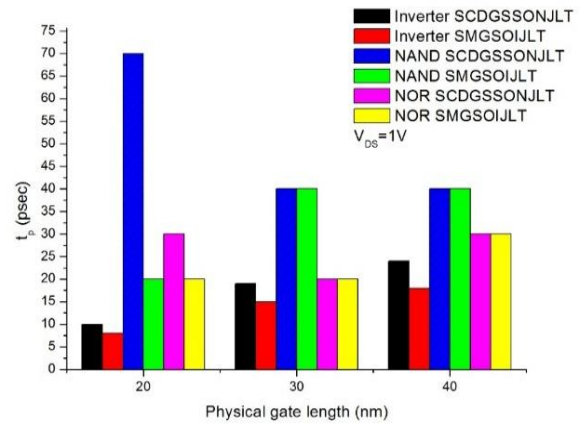


Figure 12. Comparison of propagation delay of CMOS inverter, NAND gate and NOR gate circuit based on SMG SOI and proposed SCDGSSON junctionless transistor at various channel length.

Figure 12 shows that variation of propagation delay of n-type SCDGSSONJLT v/s SMG SOI JLT at $V_{SGS}=0.5V$, $V_{DD}=1V$, main gate= $4.77eV$, side gate= $4.5eV$, $N_D=0.4 \times 10^{18} \text{ cm}^{-3}$. SCDGSSONJLT propagation delay is almost equal compare to SMGSOIJLT's NAND and NOR gate. Propagation delay τ_p decreases as channel length increases at $V_{DS}=1V$. Proposed SCDGSSONJLT propagation delay values are 10ps and 50ps at $V_{DS}=1V$, $0.5V$ respectively at channel length of 20nm. Propagation delay of SCDGSSONJLT NAND is improved by 34% compared to NAND gate of SMGSOIJLT at channel length 30 and 40 nm and $V_{DS}=0.5V$. When SCDGSSONJLT main gate length is kept constant and side gate length increases then performance of SCDGSSONJLT logic gate improves.

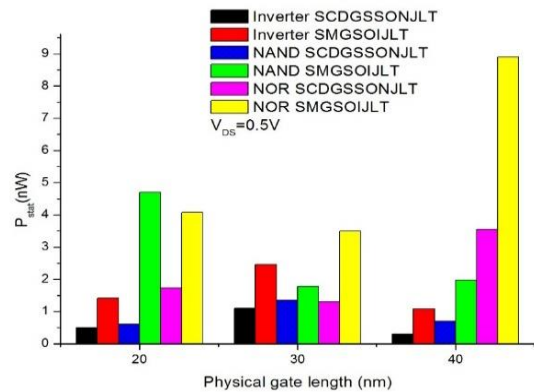


Figure 13. Comparison of static power dissipation of CMOS inverter, NAND gate and NOR gate circuit based on SMG SOI and proposed SCDGSSON junctionless transistor at various channel length.

Figure 13. shows the comparison of static power dissipation of CMOS NAND, NOR and Inverter gate circuits of SMG SOI JLT and proposed SCDGSSONJLT. The significant reduction in both P_{static} and τ_p at minimum supply voltage observe the suitability of the proposed SCDGSSONJLT for low power CMOS logic circuits. At $V_{DS}=0.5V$, the SCDGSSONJLT inverter static power dissipation is 0.6nW and that of SMGSOIJLT inverter is 4.7nW. The SCDGSSONJLT NOR gate static power dissipation is 1.73 nW and that of SMGSOIJLT is 4nW at channel length 20nm. The static power dissipation of SCDGSSONJLT NAND gate is 1.35 nW, and that of SMGSOIJLT is 1.78nW at channel length 30nm. It has been observed that SCDGSSONJLT logic gate has good performance at low power. Table 4 summarize the ON current and threshold voltage of n and p channel of SCDGSSONJLT and SMGSOIJLT. It has been observed that 44% maximum ON current of SCDGSSONJLT as compared to SMGSOIJLT at channel length 30nm. Maximum σV_{th} of n channel SCDGSSONJLT is 370mV and SMGSOIJLT is 380mV. Average threshold voltage for SCDGSSONJLT is 560mV and it is suitable for low power device at $V_{DS}=0.5V$. For SMGSOIJLT average threshold voltage is 386mV. The hole density and electric field distribution in the middle of the channel when device operated in the off-state. When device is in the off-state, the channel region to be almost completely depleted, the bulk conduction of holes is reduced. The hole mobility hovers around 40 cm^2/vs . in p-type silicon for high doping concentration. The threshold voltage of p-type SCDGSSONJLT increases.

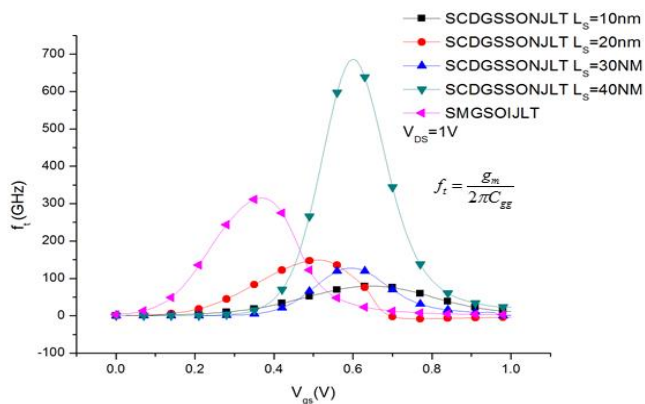


Figure 14. Cut-off frequency f_t versus gate to source voltage V_{GS} characteristics of n channel different side gate length of SCDGSSON and n type SMG SOI at $V_{DS}=1V$.

The cut-off frequency v/s gate to source voltage characteristics of n channel different side gate length of SCDGSSONJLT and SMG SOI JLT at channel length 20nm and $V_{DS}=1V$ are shown in Figure 14. The cut-off frequency f_t formula can be observed as the following equations [27-29].

$$f_t = \frac{g_m}{2\pi C_{gg}} \quad (8)$$

Where, C_{gg} is gate capacitance and g_m is transconductance. Due to higher current conductivity of SCDGSSONJLT at side gate length 40nm, the cut-off frequency f_t is maximum than that of SMG SOI JLT and SCDGSSONJLT at side gate lengths of 10nm, 20nm and 30nm. The value of f_t for SMGSOIJLT, SCDGSSONJLT are 300 GHz, 700 GHz respectively at $V_{GS}=0.6V$ and $V_{DS}=1V$ respectively. The value of SCDGSSONJLT increases due to dual gate stack gate material and in silicon on nothing technique no charge is accumulate in air. It has been observed that SCDGSSONJLT cut off frequency is improved as compared to SMGSOIJLT by 54%.

V. CONCLUSION

- The proposed device SCDGSSONJLT performs better than SMG SOI JLT. The subthreshold slope, DIBL, and cut-off frequency are improved by 20%, 20% and 39% respectively over the SMG SOI JLT.
- Three CMOS circuits have been proposed namely, Inverter, NAND and NOR gate
- The proposed device CMOS inverter fall time T_f (pS) and noise margin are improved by 50% and 10% respectively, as compared to SMG SOI JLT
- The static power dissipation in proposed SCDGSSONJLT device is reduced by 45% ,81% and 83% respectively over the SMGSOIJLT at $V_{DD}=0.5V$.
- The improvement in Propagation delay of SCDGSSONJLT NOR gate at 20nm, 30nm and 40nm is 40%, 50% and 40% respectively, as compared to SCSOIJLT.
- Although the lower gate capacitance in junctionless SCDGSSONJLT suppresses the undershoot effect in the circuit, the Cut off frequency of SCDGSSONJLT improves by 54% compared to SMGSOIJLT.

ACKNOWLEDGEMENT

This work has been funded by BCUD Savitribai Phule Pune University, Pune. Authors would like to thank VNIT Nagpur and Amit Saini for technical support.

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